



BOX AFTER FINAL

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In re the Application of:

Tae-Wan KIM et al.

Art Unit: 1763

Serial No. 10/713,258

Examiner: Rudy Zervigon

Filed: November 17, 2003

Confirmation No. 4771

For: GAS INJECTION APPARATUS FOR
SEMICONDUCTOR PROCESSING SYSTEM

Attorney Docket No. 249/410

REPLY UNDER 37 C.F.R. § 1.116

Mail Stop: Amendment After Final
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

INTRODUCTORY COMMENTS

In response to the Office action mailed on July 13, 2006, the following remarks are respectfully submitted in connection with the above-identified application:

A Listing of the Claims begins on page 2 of this paper.

Remarks begin on page 7 of this paper.